

IN THE CLAIMS:

Please amend claims 14-23. Please add new claims 24 - 27.

Claims 1 - 13 (Canceled)

14. (Currently amended) Method for measuring the geometry and surface evenness of one side of a moving metal strip by producing a pattern on that one side of the metal surface to be measured using a light source, wherein said light source can produce a changeable pattern on the metal surface by means of projection with the aid of a transparency, and a camera, wherein a pattern usable for the measuring situation is selected and produced.

15. (Previously presented) Method according to claim 14, characterized in that the pattern is produced with the aid of a liquid-crystal device.

16. (Previously presented) Method according to claim 14, characterized in filtering elastic form changes using the initially detected peaks and separating the peaks according to different frequencies and wavelength on account of strip movements.

17. (Previously presented) Method according to claim 14, characterized by measuring by using the edge boundary of the strip.

18. (Previously presented) Method according to claim 17, characterized in that the strip width or cut length is determined from the edge boundary.

19. (Previously presented) Method according to claim 14, characterized in measuring the geometry of a known element of a measuring device and generating by computation a reference plane and a reference phase image from said measured geometry.

20. (Currently amended) Method for measuring the geometry and surface evenness of one side of a moving metal strip by producing a pattern on the metal surface to be measured using a light source, and a camera, wherein the pattern on that one side of the metal surface to be measured is produced by means of projection with the aid of transparency, characterized in filtering elastic form changes using the initially detected peaks and separating the peaks according to different frequencies and wavelength on account of strip movements.

21. (Currently amended) Method for measuring the geometry and surface evenness of one side of a moving metal strip by producing a pattern on that one side of the metal strip to be measured using a light source, and a camera, wherein the pattern on the metal surface to be measured is produced by means of projection with the aid of transparency, characterized by measuring by using the edge boundary of the strip.

22. (Previously presented) Method according to claim 21, characterized in that the strip width or cut length is determined from the edge boundary.

23. (Currently amended) Method for measuring the geometry and surface evenness of one side of a moving metal strip by producing a pattern on that one side of the metal surface to be measured using a light source, and a camera, wherein the pattern on the metal surface to be measured is produced by means of projection with the aid of transparency, characterized in measuring the geometry of a known element of a measuring device and generating by computation a reference plane and a reference phase image from said measured geometry.

24. (New) Method according to claim 14, characterized in that a line pattern is produced on the metal surface.

25. (New) Method according to claim 20, characterized in that a line pattern is produced on the metal surface.

26. (New) Method according to claim 21, characterized in that a line pattern is produced on the metal surface.

27. (New) Method according to claim 23, characterized in that a line pattern is produced on the metal surface.